



Laser Beam Scanning (LBS): The Ideal Solution for AR Wearable Applications

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SPIE. AR VR MR

Definitions





Virtual Reality - Occluded view and a fully immersive experience





Augmented Reality - Simple digital content is overlaid onto physical world





Mixed Reality – Physical and Virtual worlds are fully merged with visually accurate depth, perspective, texture, shade etc.



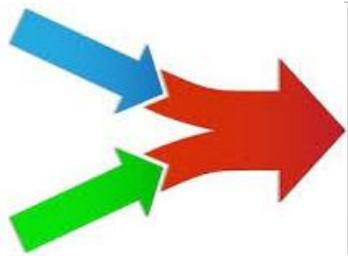
Source: https://www.forbes.com/sites/solrogers/2019/09/11/what-we-know-about-hololens-2/#2885224d4662



Source: https://variety.com/2019/digital/news/magic-leap-mobile-ar-1203109944/

life, augmented

The Main Challenge





- > To achieve the desired form factor key determinants, to first order, are:
 - Near-to-eye compact display technology
 - Highly efficient combiner optics technology
- ➤ Start with simple and broadly useful applications → smart glasses
- Then, add additional functionality as technology & solutions mature

Key requirements for AR wearable devices

Goal: Head-up, Hands-free, All-day-wearable AR glasses which means glasses must be usable, comfortable with the requisite performance

Indoor and outdoor use

Form factor

Low Power (system)

Light weight

Low latency (motion to photon)

Range of FoV

Range of resolution

Eyebox size



Peak brightness > 1000 cd/m2 (transparent lenses)



Fashionable eyeglasses



< 1W



< 70g



< 4ms



 $30^{\circ} - 40^{\circ} (AR) \text{ to } > 80^{\circ} (MR/XR)$



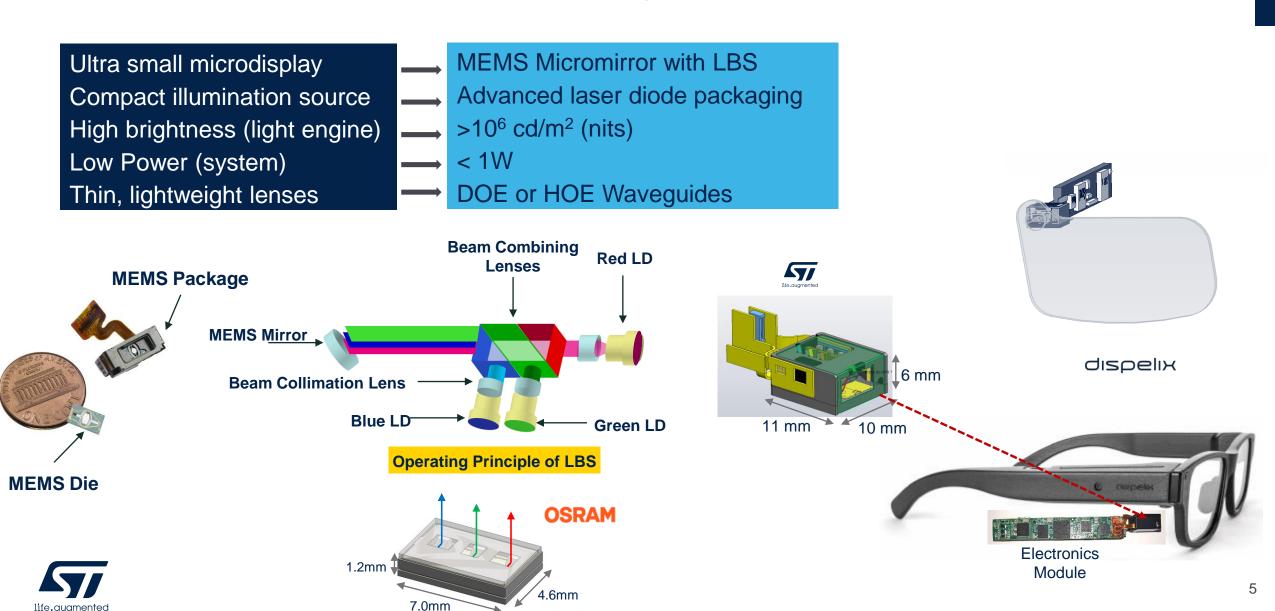
720P (AR) to > 1400P (MR/XR)



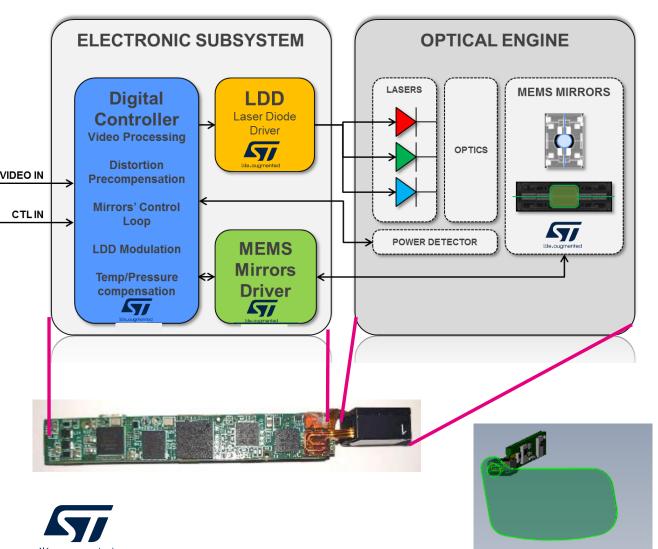
> 10mm x 10mm



Laser Beam Scanning (LBS) – The Ideal Solution



LBS Reference Design Architecture



MEMS Mirrors







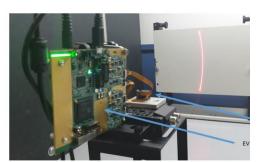
Laser Diodes Drivers

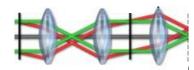
- <500ps rise/fall time for crisp pixels
- Ultra low power Optimized for AR
- 3 / 4 channels (RGB / + IR)

Control Loops and Video

- HW / SW Mirror control loop
- Laser control loop
- Calibration
- Video processing

Relay Optics

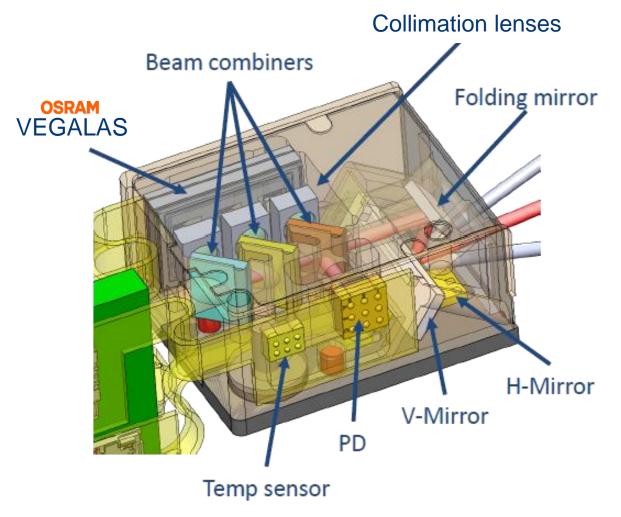








Anatomy of the ST LBS Optical Module



https://www.spie.org/PWO/conferencedetails/moems-miniaturized-systems?SSO=1#session-1

Session 6: Novel Optical Components II



Putting it All Together – A Proof-of-Concept



Demo Specification		
FOV (diagonal)*	30°	24°(H)x18°(V)
Brightness	1300	cd/m ²
Image Aspect Ratio	4:3	
Eyebox	10 x 10	mm
Eye Relief	16	mm
Color	RGB	
Resolution	33	pixels/deg
Fresh Rate	60	Hz
Full System Weight	58	g



^{*} Note: The FoV of the MEMS Mirror scanner is 56° diagonal

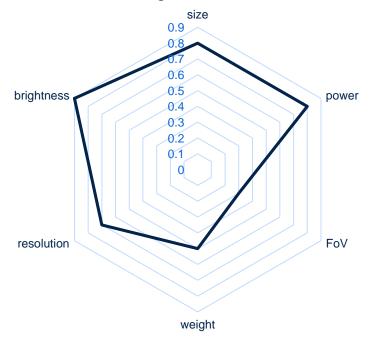
Images as Seen Through the Glasses





Trade-offs (system consideration)

AR Glasses Design Tradeoff Considerations



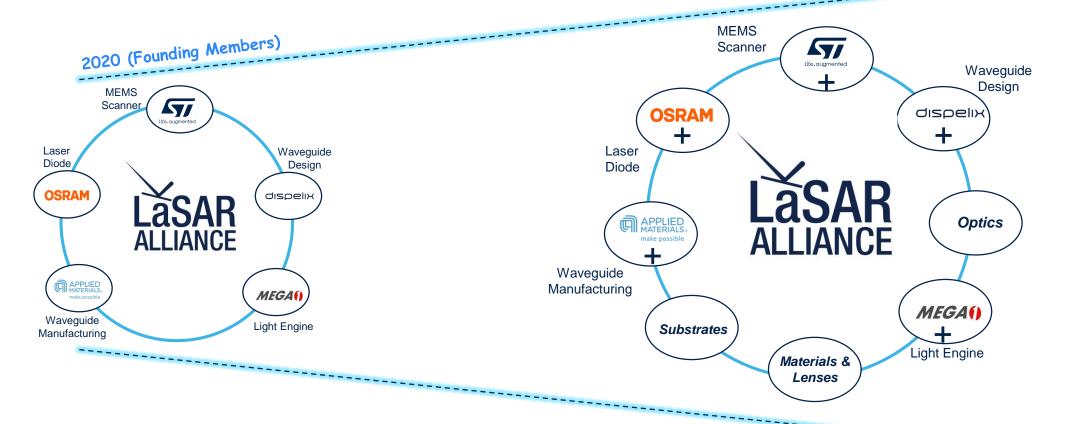
Example only

- Design of AR wearables must be holistic in nature
- Optimize for the application
 - Simple text, symbology and graphical overlay
 - FoV ~ 30°-40°, >10mm eyebox, >1000 nits, <70g, monocular, eyeglass style
 - Fully immersive experience with holographic rendering
 - FoV >80°, >10mm eyebox, >500 nits, >1440P, <200g, binocular, HMD style
- LBS addresses a number of constraints and challenges



It Takes a Village: LaSAR Alliance Ecosystem

2021 (Expanded Ecosystem)





More Partners to be Announced &

Open to More Members

Join the Alliance!

Thank you

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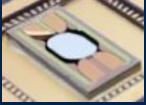
A wide range of mirror technologies in mass production

ST is the leader in LBS solutions with more than 12 million mirrors shipped to date

In-plane comb fingers High aspect ratio DRIE silicon etch for comb drive ELECTROSTATI actuators (silicon thickness ≥40um), allowing both quasistatic and resonant operation Use of wafer-to-wafer bonding techniques to realize 3D integrated structures Staggered comb fingers Thick metal layers integrated with ELECTROMAGNETIC silicon mechanical structure • Thick metal ECD growth (>20um) to allow low resistance coil actuator Integrated piezoresistive position sensors Thin (160um) finished holed wafers in production Thick metal cross section for coil



Thin Film PZT Mirror

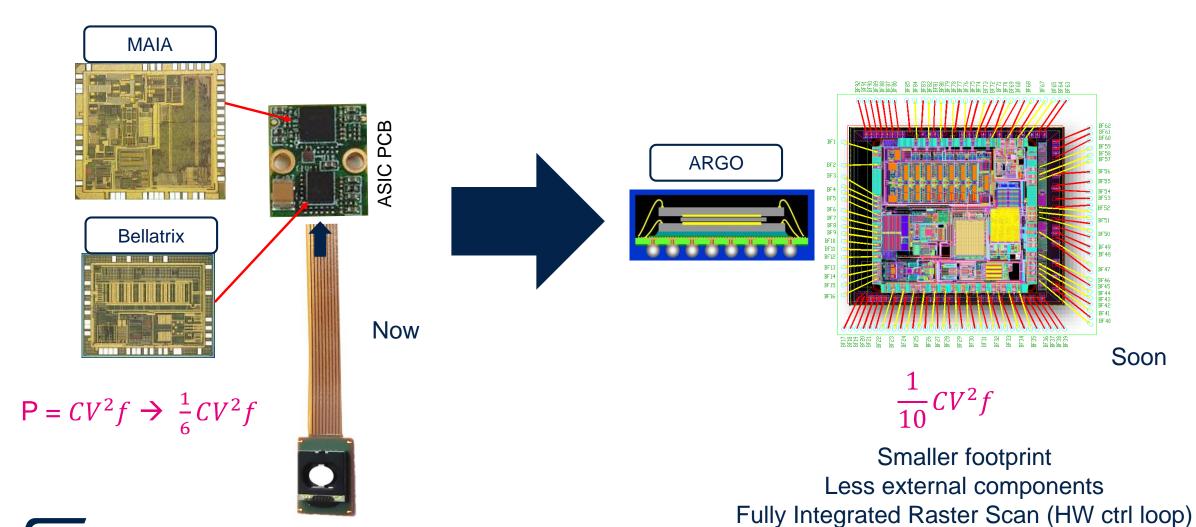




- Thin Film PZT (≤2um), in Mass Production
- Integrated piezoresistive position sensor
- Use of wafer-to-wafer bonding for 3D integrated structures



High Efficiency TF PZT Drivers





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